

## PATENT

Atty. Dkt. AMAT/2592.C9/DSM/LOW K/JW



In re Application of:  
Gaillard, et al.

Serial No.: 10/789,209

Filed: February 27, 2004

Confirmation No.: Unknown

For: Method of Decreasing the  
K Value in SIOC Layer  
Deposited by Chemical  
Vapor Deposition

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Group Art Unit: Unknown

Examiner: Unknown

**MAIL STOP AMENDMENT**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**CERTIFICATE OF MAILING**

37 CFR 1.8

I hereby certify that this correspondence is being deposited on 5/19, 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

5/19/04

Date \_\_\_\_\_

Keith & Ruth

**Signature**

Dear Sir:

## PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as shown below. **Amendments to the Specification** begin on page 2. **The Pending Claims** begin on page 3. **Remarks** begin on page 7.